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### (54) PLANE ADJUSTING MECHANISM FOR PROBE CONTACT SYSTEM

(57)Abstract:

**PROBLEM TO BE SOLVED:** To provide a probe contact system wherein the distance between the tip of a contactor and a contact target is adjusted by a simple low-cost mechanism.

**SOLUTION:** This plane adjusting mechanism is composed of a contact substrate with a large number of contactors; a probe card for forming electrical connection between the contactors and a test head of a semiconductor test system; conductive elastomer provided between the contact substrate and the probe card; connecting members for connecting the contact substrate and the probe card in three point positions on the contact substrate and rotating to adjust the distance between the contact substrate and the probe card; gap sensors provided in proximity to the respective point positions of the contact substrate to measure a gap between the contact substrate and a target substrate; and a rotating-adjusting device for rotating the connecting members so that the gap between the contact substrate and the target substrate is the same in three point positions.

